Docket No.: 52352-372 **PATENT** 

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Jeffrey A. SHIELDS, et al.

Serial No.: 09/498,336

Filed: February 04, 2000

CF4 + H2O PLASMA ASHING FOR REDUCTION OF CONTACT/VIA **RESISTANCE** 

Group Art Unit: 1765

Examiner: V. Perez-Ramos

**AMENDMENT** 

Commissioner for Patents Washington, DC 20231

Sir:

For:

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The following Amendment and Remarks are submitted in response to the Office Action dated June 16, 2002.

## IN THE SPECIFICATION:

Page 1, please amend the first full paragraph under the caption "RELATED APPLICATION" as follows:

This application	contains subject matter similar	r to subject matter disclosed in
copending U.S. Patent A	application Serial No. [	<u>09/498,335</u> filed on
February 4, 2000 [	(Our Docket No. 52352-37	71)].